**Pump Priming Pro Forma**

The aim of pump priming is to provide a limited number of growths (including any necessary calibrations) in order to try out ideas before a full grant application. As such proposals should typically aim for 1-3 deliverable structures. In order for us to understand the complexity of a potential request it is necessary to contact NEF ([epitaxyfacility@sheffield.ac.uk](mailto:epitaxyfacility@sheffield.ac.uk)) before submitting this form. You will then be put in contact with the relevant member of the growth team for initial discussions.

With the exception of Results that relate to the epitaxial process the applicant's institution will own the Results and all Intellectual Property in them. The NEF partner delivering the work shall own Results that relate to the epitaxial process and may use any resulting new capability to improve the service it offers to the wider community. If you require a discussion of any potential IP related issues before the application is sent to the panel for evaluation please tick this box.

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If your application is successful: Providing NEF's service to you as part the pump priming scheme establishes a collaboration between the two parties. Following guidelines from the EPSRC, it is expected that any research article arising from the research on wafers provided by the NEF is discussed with the appropriate members of the NEF in advance of publication. This is to determine and agree authorship or acknowledgment in relation to the intellectual input to the research results obtained.

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| **Name of applicant** |  |
| **Institute** |  |
| **Proposed title of the project** |  |
| **NEF contact(s) you have discussed this application with** |  |
| **Would you be considered an Early Career Researcher by UKRI?** | Yes No |

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| **What is the scientific and technical background to the proposed pump-priming activity?**  **(200 words max)** |
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| **Indicate whether this proposal could be considered materials development, novel device structure design/testing or establishing a capability within the NEF.** |
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| **How many wafers are requested? (Delivered Structures)** |
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| **Specifically, what are the details of each wafer?**  **e.g. substrate, layer structure, compositional or thickness tolerances of layers, doping levels** |
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| **What characterisation will be required to assess the grown wafers and do you have access to such facilities if required to provide feedback on calibration structures?** |
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| **What are the expected outcomes of the pump priming activity and how will success be measured?** |
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| **Explain how the pump priming activity will lead to a full funding application and what will be its scope. (200 words max), e.g. number of wafers; fabrication processes; devices etc., required in the proposal**  **NB. Applicants must first seek confirmation from NEF personnel that this feasibility application is within the capability of the Facility.** |
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| **Are there already well-established growth activities in this area in research groups in the UK or worldwide?** |
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| **Comments from NEF personnel associated with the pump prime activity.** |
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Name of applicant completing the form: ………………………………………………………..

Date: ……………………………....

Please send the completed form to the email address: [epitaxyfacility@sheffield.ac.uk](mailto:epitaxyfacility@sheffield.ac.uk)